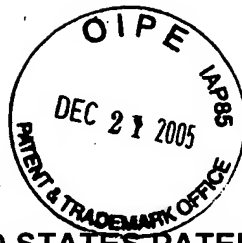


Docket No. EATNP147US

02-IMP-056



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re **PATENT** application of:

Applicant: Peter Kellerman et al.
Application No.: 10/642,939
For: MEMS Based Multi-Polar Electrostatic Chuck
Filing Date: August 18, 2003
Examiner: Ann Thi Hoang
Art Unit: 2836

REPLY TO OFFICE ACTION DATED OCTOBER 6, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following remarks.